

IN THE SPECIFICATION

Please replace the title of the invention as it appears on page 1, line 1, with the following rewritten title:

METHOD OF MANUFACTURING A SEMICONDUCTOR DEVICE AND METHOD OF
MANUFACTURING SAME HAVING SELECTIVE EPITAXIAL SILICON LAYER ON
CONTACT PADS

IN THE ABSTRACT

Please replace the title of the invention as it appears on page 21, line 1, with the following rewritten title:

METHOD OF MANUFACTURING A SEMICONDUCTOR DEVICE AND METHOD OF
MANUFACTURING SAME HAVING SELECTIVE EPITAXIAL SILICON LAYER ON
CONTACT PADS